



IPW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2813
Examiner: Jack S. J. Chen

In Re PATENT APPLICATION Of:

Applicant(s): Toshikazu MIZUKOSHI)

Serial No.: 10/635,506)

Filed: August 7, 2003)

For: METHOD OF FABRICATING A)
SEMICONDUCTOR DEVICE TRENCH)
HAVING AN OXIDE FILM ON A)
CORNERED PORTION THEREOF)
(As Amended))

Docket No.: OKI 361)

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Examiner's Action mailed on May 5, 2004, please amend the above-identified application as follows:

FEE ENCLOSED:\$ *0*
Please charge any further
fee to our Deposit Account
No. 18-0002

TITLE AMENDMENTS:

Please delete the current Title and substitute it with the new Title as follows:

--METHOD OF FABRICATING A SEMICONDUCTOR DEVICE TRENCH HAVING AN OXIDE FILM ON A CORNERED PORTION THEREOF--.